





APPLICATION NO.	FILING DATE	FIRST NAMED INVENTOR	ATTORNEY DOCKET NO.	CONFIRMATION NO.	
10/092,795	03/06/2002	Padmapani C. Nallan	7017/ETCH/CONE	3410	
32588	7590 04/23/2003				
APPLIED MATERIALS, INC.			EXAMINER		
	BLVD. M/S 2061 RA, CA 95050		NGUYEN, TUAN H		
			ART UNIT	PAPER NUMBER	
			2813	7	
			DATE MAILED: 04/23/2003		

Please find below and/or attached an Office communication concerning this application or proceeding.

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	Application No.		Applicant(s)					
	10/092,795		NALLAN ET AL.					
Office Action Summary	Examin r		Art Unit					
	Tuan H. Nguyen		2813	-				
The MAILING DATE of this communication app ars on the cover shet with the correspondence address Period for Reply								
A SHORTENED STATUTORY PERIOD FOR REPLY THE MAILING DATE OF THIS COMMUNICATION.  - Extensions of time may be available under the provisions of 37 CFR 1.13 after SIX (6) MONTHS from the mailing date of this communication.  - If the period for reply specified above is less than thirty (30) days, a reply If NO period for reply is specified above, the maximum statutory period of Failure to reply within the set or extended period for reply will, by statute - Any reply received by the Office later than three months after the mailing earned patent term adjustment. See 37 CFR 1.704(b).  Status	36(a). In no event, however, may within the statutory minimum of vill apply and will expire SIX (6) N cause the application to become	y a reply be tim thirty (30) days MONTHS from e ABANDONEI	ely filed s will be considered timel the mailing date of this c O (35 U.S.C. § 133).					
1) Responsive to communication(s) filed on <u>05 F</u>	ebruary 2003 .							
2a) ☐ This action is <b>FINAL</b> . 2b) ☑ Th	is action is non-final.							
3) Since this application is in condition for allowatelosed in accordance with the practice under Disposition of Claims				ne merits is				
4)⊠ Claim(s) <u>1-34</u> is/are pending in the application	١.							
4a) Of the above claim(s) 18-34 is/are withdraw	4a) Of the above claim(s) <u>18-34</u> is/are withdrawn from consideration.							
S)⊠ Claim(s) <u>17</u> is/are allowed.								
6)⊠ Claim(s) <u>1,2 and 4-16</u> is/are rejected.								
7)⊠ Claim(s) <u>3</u> is/are objected to.								
8) Claim(s) are subject to restriction and/o	r election requirement.							
Application Papers								
9)☐ The specification is objected to by the Examine								
10) ☐ The drawing(s) filed on is/are: a) ☐ accept	oted or b) objected to b	by the Exar	miner.					
Applicant may not request that any objection to the drawing(s) be held in abeyance. See 37 CFR 1.85(a).								
11) The proposed drawing correction filed on is: a) approved b) disapproved by the Examiner.								
If approved, corrected drawings are required in rep	•							
12) The oath or declaration is objected to by the Ex	aminer.							
Priority under 35 U.S.C. §§ 119 and 120		0.0440/						
13) Acknowledgment is made of a claim for foreign	n priority under 35 U.S.	C. § 119(a	)-(a) or (t).					
a) ☐ All b) ☐ Some * c) ☐ None of:	a hava haan naasivad							
1. Certified copies of the priority document		A	an Na					
2. Certified copies of the priority document		• •	<del>-</del>	Stone				
<ul><li>3. Copies of the certified copies of the prior</li><li>application from the International Bu</li><li>* See the attached detailed Office action for a list</li></ul>	reau (PCT Rule 17.2(a	<b>))</b> .		Stage				
14) Acknowledgment is made of a claim for domesti	c priority under 35 U.S.	.C. § 119(e	e) (to a provisiona	l application).				
<ul> <li>a)  The translation of the foreign language pro</li> <li>15)  Acknowledgment is made of a claim for domest</li> </ul>	• •							
Attachment(s)								
<ol> <li>Notice of References Cited (PTO-892)</li> <li>Notice of Draftsperson's Patent Drawing Review (PTO-948)</li> <li>Information Disclosure Statement(s) (PTO-1449) Paper No(s)</li></ol>	5) Notice	of Informal F	r (PTO-413) Paper No Patent Application (PT					



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# Claim Rejections - 35 USC § 112

The following is a quotation of the second paragraph of 35 U.S.C. 112:

The specification shall conclude with one or more claims particularly pointing out and distinctly claiming the subject matter which the applicant regards as his invention.

Claims 15-16 are rejected under 35 U.S.C. 112, second paragraph, as being indefinite for failing to particularly point out and distinctly claim the subject matter which applicant regards as the invention.

In claims 15, 16, lines 2, "said hafnium-oxide" lacks antecedent basis.

## Claim Rejections - 35 USC § 102

The following is a quotation of the appropriate paragraphs of 35 U.S.C. 102 that form the basis for the rejections under this section made in this Office action:

A person shall be entitled to a patent unless -

- (b) the invention was patented or described in a printed publication in this or a foreign country or in public use or on sale in this country, more than one year prior to the date of application for patent in the United States.
- (e) the invention was described in a patent granted on an application for patent by another filed in the United States before the invention thereof by the applicant for patent, or on an international application by another who has fulfilled the requirements of paragraphs (1), (2), and (4) of section 371(c) of this title before the invention thereof by the applicant for patent.

The changes made to 35 U.S.C. 102(e) by the American Inventors Protection Act of 1999 (AIPA) and the Intellectual Property and High Technology Technical Amendments Act of 2002 do not apply when the reference is a U.S. patent resulting directly or indirectly from an international application filed before November 29, 2000.

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Therefore, the prior art date of the reference is determined under 35 U.S.C. 102(e) prior to the amendment by the AIPA (pre-AIPA 35 U.S.C. 102(e)).

Claims 1, 2, 4, 7 are rejected under 35 U.S.C. 102(b) as being anticipated by Moise et al.(cited ref.).

See Moise et al., see particularly paragraph [0097] and step 4 in table on page 6 which discloses the claimed method of etching a layer of dielectric PZT having a dielectric constant greater than 4 by exposing the PZT dielectric layer 608 to a plasma comprising a reducing gas of oxygen and a halogen containing gas of chlorine. See also paragraphs [0159], [0160] on page 11, paragraphs [0167] on page 12, and paragraph [0173] on page 13 for the etching of PZT or BST dielectric layer using Cl<sub>2</sub> plus O<sub>2</sub>.

Claims 1, 2, 4, 7 are rejected under 35 U.S.C. 102(e) as being anticipated by Iguchi (cited ref.).

See Iguchi, particularly embodiment 3 on pages 9-10 and related figs. 20-26 which show the step of etching high dielectric constant layer 38A of either PZT, BST, PLT, PLZT, SBT ([0182]) by exposing the dielectric layer to a plasma comprising chlorine as the main gas and oxygen as a reducing gas.

### Claim Rejections - 35 USC § 103

The following is a quotation of 35 U.S.C. 103(a) which forms the basis for all obviousness rejections set forth in this Office action:

(a) A patent may not be obtained though the invention is not identically disclosed or described as set forth in section 102 of this title, if the differences between the subject matter sought to be patented and the prior art are such that the subject matter as a whole would have been obvious at the time the invention was made to a person having ordinary skill in the art to which said subject matter pertains. Patentability shall not be negatived by the manner in which the invention was made.

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Claims 5, 6, 8-14 are rejected under 35 U.S.C. 103(a) as being unpatentable over Moise et al..

Moise et al., particularly paragraph [0097] and step 4 in table on page 6; paragraphs [0159], [0160] on page 11, paragraphs [0167] on page 12, and paragraph [0173] on page 13 disclose substantially the claimed method of etching a layer of dielectric PZT having a dielectric constant greater than 4 by exposing the PZT dielectric layer 608 to a plasma comprising a reducing gas of oxygen and a halogen containing gas of chlorine. See also for the etching of PZT or BST dielectric layer using Cl<sub>2</sub> plus O<sub>2</sub>.

Moise et al. does not particularly use CO as an oxygen source; however, in table on page 11, paragraph [0160], Moise et al. suggests the alternating oxygen source such as either O<sub>2</sub> or CO.

It would have been obvious to one having ordinary skill in the art at the time the invention was made to have replaced  $O_2$  with CO as a gas source in the process of plasma etching the dielectric layer, since the substitution of art recognized equivalence as suggested by Moise et al. would have been within the level of those skilled in the art.

With respect to claims 8-14, it would have been also obvious to those skill in the art to select a suitable control parameter such as power, flow rate, pressure for obtaining the best result

#### Allowable Subject Matter

Claim 17 is allowed.

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Claim 3 is objected to as being dependent upon a rejected base claim, but would be allowable if rewritten in independent form including all of the limitations of the base claim and any intervening claims.

The following is a statement of reasons for the indication of allowable subject matter: None of the references of record teaches or suggests the claimed method for etching hafnium-oxide by plasma using chlorine and CO.

## Response to Arguments

Applicant's arguments with respect to claims 1-17 have been considered but are most in view of the new ground(s) of rejection.

It is agreed that Kim et al. reference in the previous Office Action discloses the etching of transition metal thin film, does not clearly teach the claimed method of etching the dielectric layer by plasma with chlorine and CO gases, therefore, it has been withdrawn.

Any inquiry concerning this communication or earlier communications from the examiner should be directed to Tuan H. Nguyen whose telephone number is 703-308-2550. The examiner can normally be reached on 9AM-5:30PM.

If attempts to reach the examiner by telephone are unsuccessful, the examiner's supervisor, Carl Whitehead Jr. can be reached on 703-308-4940. The fax phone numbers for the organization where this application or proceeding is assigned are 703-872-9318 for regular communications and 703-872-9319 for After Final communications.

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Any inquiry of a general nature or relating to the status of this application or proceeding should be directed to the receptionist whose telephone number is 703-308-0956.

Tuan H. Nguyen Primary Examiner Art Unit 2813

TN April 21, 2003